BETTE THE UNITED STATES

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THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

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IZUMI, Katsutoshi, et al.

Group Art Unit: 2823

Serial No.: 10/708,593

Examiner: Michelle ESTRADA

Filed: March 12, 2004

P.T.O. Confirmation No.: 2592

For: METHOD FOR MANUFACTURING BURIED INSULATING LAYER

TYPE SINGLE CRYSTAL SILICON CARBIDE SUBSTRATE (AS AMENDED)

RESPONSE TO THE RESTRICTION REQUIREMENT DATED January 11, 2005

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Date: February 7, 2005

Sir:

This paper is submitted in response to the Official Action dated January 11, 2005.

In the Action, restriction is required between Group (I), Claims 1-6; and Group (II),

Claims 7-15.

Applicants hereby elect the subject matter of Group (I), Claims 1-6 for prosecution in this application. This election is made without traverse, it being understood that the applicants' rights to the filing of a divisional application directed to the non-elected subject matter under 35 USC 120 and 35 USC 121 are retained.

In the event that this paper is not timely filed, applicants hereby petition for an appropriate extension of time. The fee for any such extension may be charged to our Deposit Account No. 01-2340.

RESPONSE TO THE RESTRICTION REQUIREMENT

filed on February 7, 2005 U.S. Patent Application No. 10/708,593

In the event any additional fees are required in connection with this response, please charge our Deposit Account No. 01-2340.

Respectfully submitted,

ARMSTRONG, KRATZ, QUINTOS, HANSON & BROOKS, LLP

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PATENT TRADEMARK OFFICE

Enclosure: Preliminary Amendment